MANUFACTURING METROLOGY TEAM

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COHERENCE SCANNING INTERFEROMETRY FOR METAL ADDITIVE MANUFACTURING

Carlos Gómez[1], Rong Su[1], Adam Thompson[1], Jack DiSciacca[2], Simon Lawes[1] and Richard Leach[1]

[1]Manufacturing Metrology Team, University of Nottingham, NG7 2RD, UK [2]Zygo Corporation, Middlefield, CT 06455 USA

Motivation

- Metal AM surfaces are rough and can be challenging to measure, due to the presence of complex features, which include high slopes, step like recesses and protuberances, and local variations in reflectance
- Coherence scanning interferometry (CSI) is a non-contact measurement method that uses a broadband light source and interference to measure surface topography and object geometry, originally designed for measuring smooth surfaces
- Recent progress in the development of the CSI technique allows a significantly enhanced detection sensitivity through advanced measurement functions, such as filtering of the source spectrum, high dynamic range (HDR) lighting levels, adjustable number of camera acquisitions over each interference fringe (i.e. oversampling) and sophisticated topography reconstruction algorithms

Objectives

- Demonstrate the feasibility of using CSI for characterising metal AM surfaces
- Evaluate the effectiveness of relevant CSI measurement settings

CSI measurements of metal AM surfaces

	Surfaces	*Sq* /µm	*Sdq*
S1	LPBF Al-Si-10Mg cube, top surface	19 ± 2	0.6 ± 0.1
S2	LPBF Al-Si-10Mg cube, side surface	20 ± 3	1.0 ± 0.2
S3	LPBF Ti-6Al-4V cube, top surface	22 ± 3	1.1 ± 0.1
S4	EBPBF Ti-6Al-4V rectangular prism, top surface	34 ± 2	1.7 ± 0.2
S5	LPBF Ti-6Al-4V cube, side surface	16 ± 2	12 ± 2

Table 1. Surface texture parameters for the test cases. An S-filter and an L-filter were applied to remove high frequency noise and long scale waviness/form

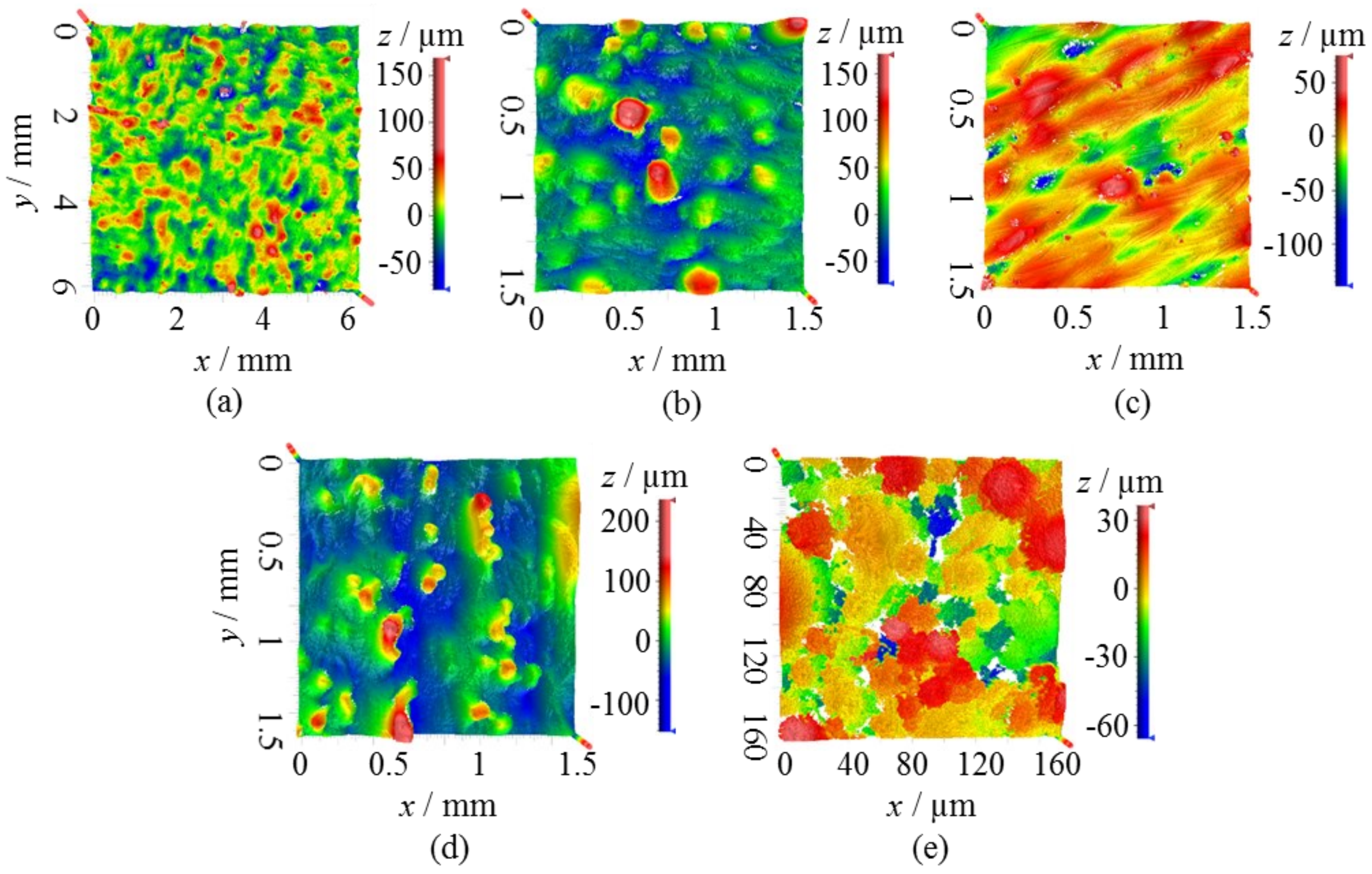

Fig. 2. CSI measurements of metal AM surfaces: (a) S1, (b) S2, (c) S3, (d) S4, and (e) S5. The 1.4× objective lens (1× zoom) was used for (a), the 5.5× objective lens (1× zoom) was used for (b, c, and d), the 50× objective lens (1× zoom) was used for (e).

Summary and outlook

- The effects of the advanced measurement functions on the measurements of several typical AM surfaces have been demonstrated. Results show that the CSI technique is feasible for measuring surface topography in metal AM
- Increasing the signal oversampling factor, with a narrow bandwidth source spectrum and the use of a coherence profile fringe analysis method will maximise data coverage without sacrificing measurement area, but measurement time may be compromised
- This study also presents insight into areas of interest for future rigorous examination, such as measurement noise and further development of guidelines for the measurement of metal AM surfaces

Method

A ZYGO NewView™ 8300 CSI system was used for this study. The experimental design covers the following aspects:

- Five common metal AM surfaces made from different materials and processes (laser powder bed fusion (LPBF), electron beam powder bed fusion (EBPBF))
- A series of measurements performed by using a combination of four objective lenses and two optical zoom factors, two spectral filters, two fringe analysis methods, five settings of signal oversampling and two HDR lighting levels. Topographic measurements are described through areal surface texture parameters *Sq* and *Sdq* and are analysed for data coverage, measurement time and area

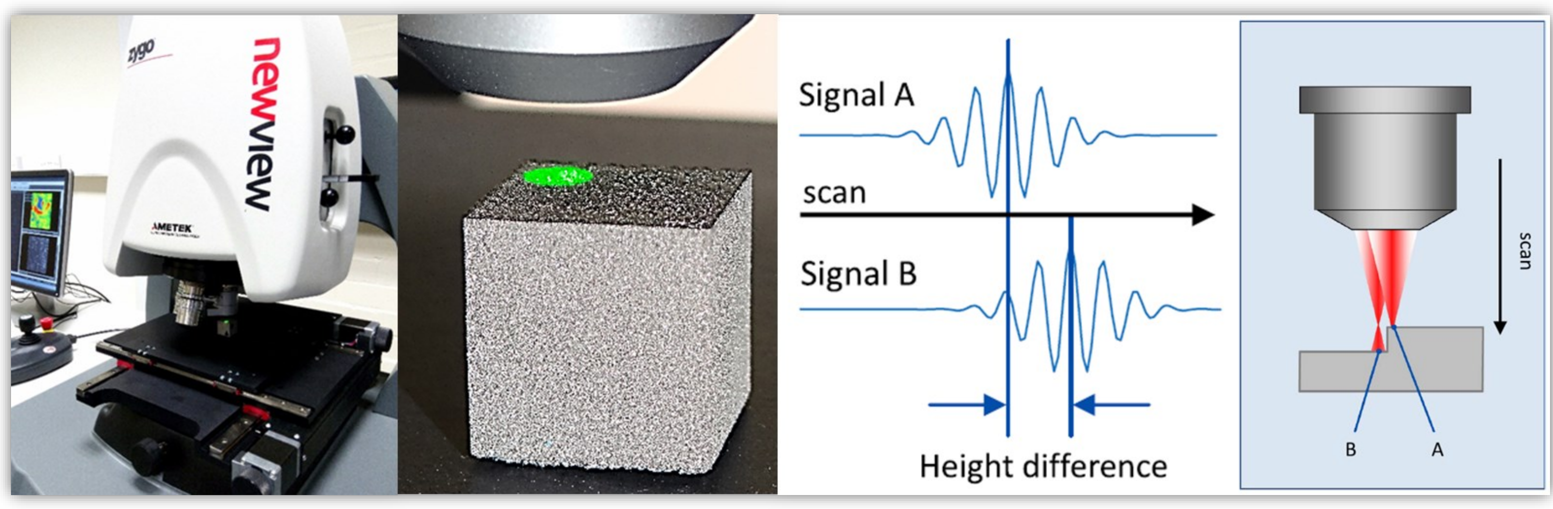

Fig. 1. CSI data acquisition (data rates are more than a million surface height points per second)

Effects of measurement functions and settings

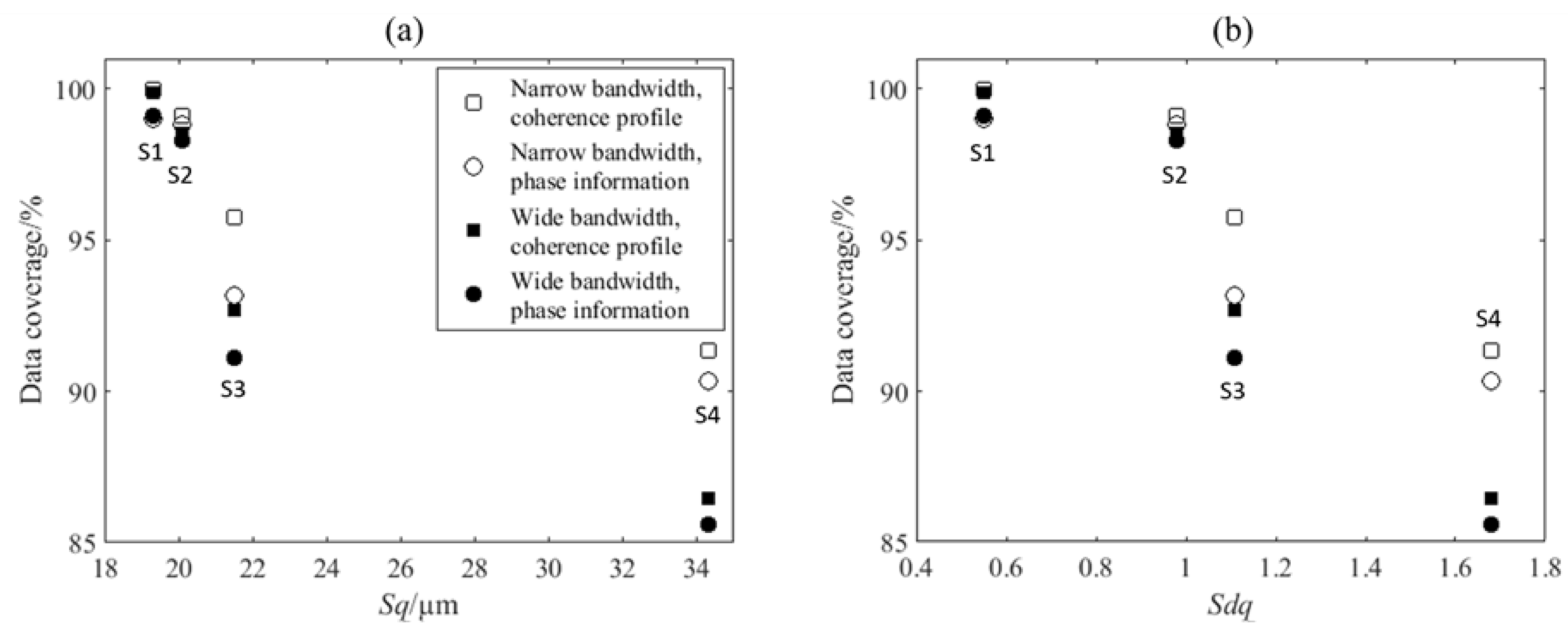

Fig. 3. Effects of spectral filtering and fringe analysis methods on data coverage. 5.5× objective lens was used. The data coverage is plotted as a function of a) Sq and b) Sdq

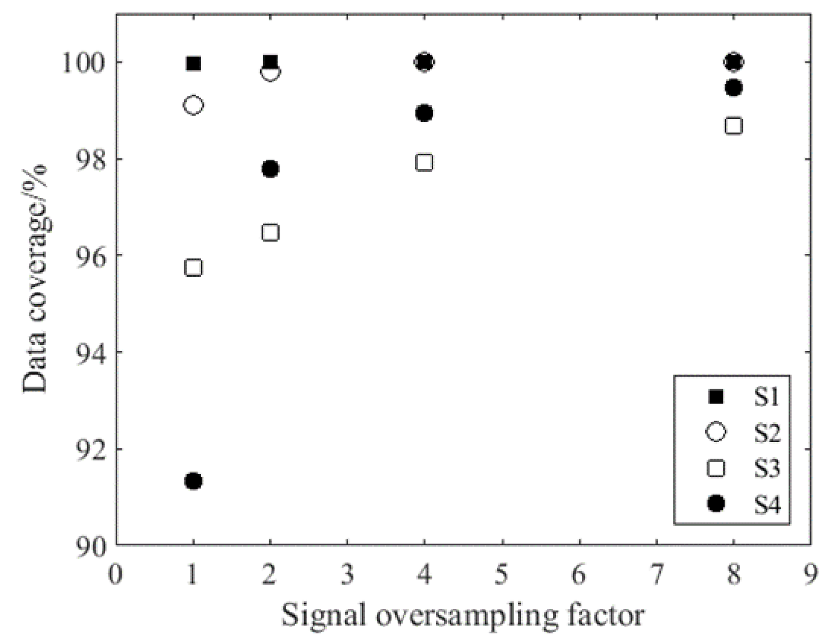

Fig. 4. Effects of signal oversampling on data coverage. 5.5× objective lens, narrow bandwidth spectrum and coherence profile fringe analysis method were used

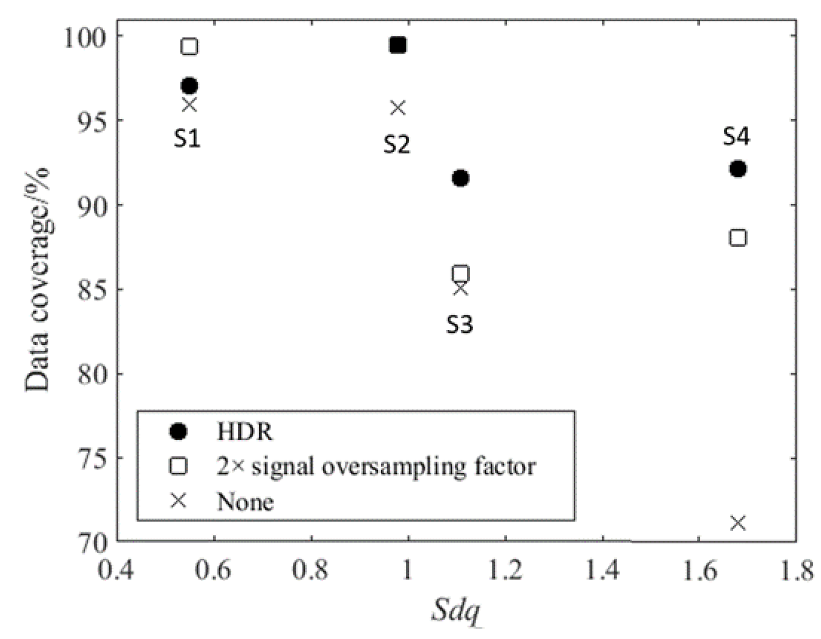

Fig. 5. Comparison between HDR and signal oversampling and a measurement performed without using advanced functions. The data coverage is plotted as a function of Sdq

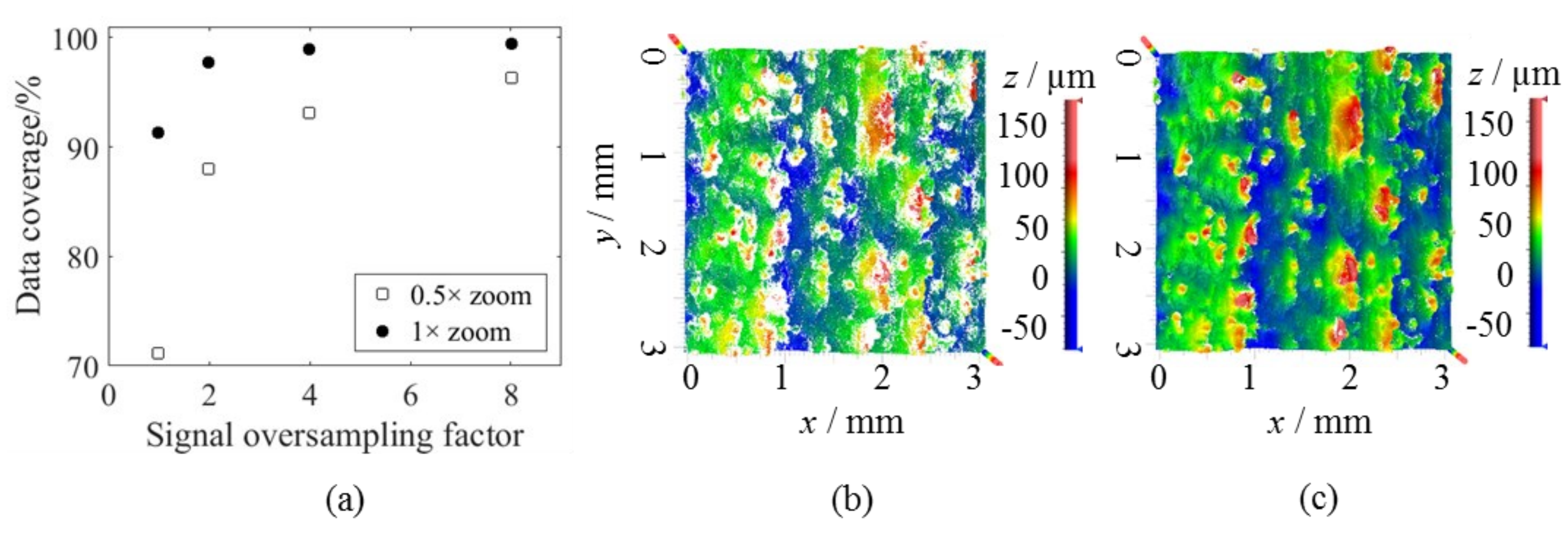

Fig. 6. Effects of signal oversampling on data coverage for S4. 5.5× objective lens, narrow bandwidth spectrum and coherence profile fringe analysis method were used. (a) The effect of the camera exposure time; (b) original measurement without using signal oversampling (0.5× zoom); and (c) result with 8× signal oversampling (0.5× zoom)